FIG.1

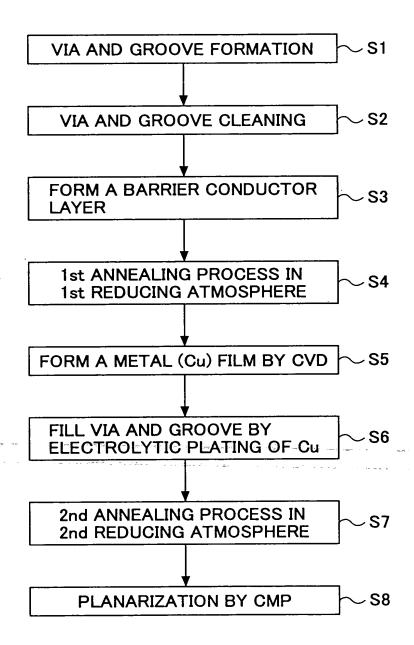


FIG. 2

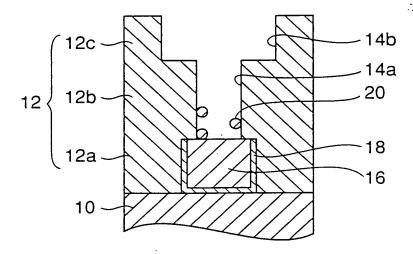


FIG. 3

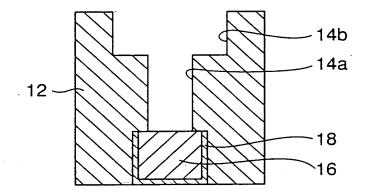


FIG. 4

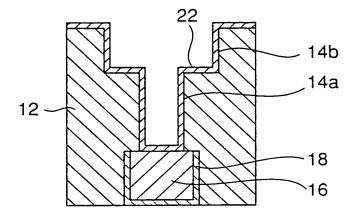


FIG. 5

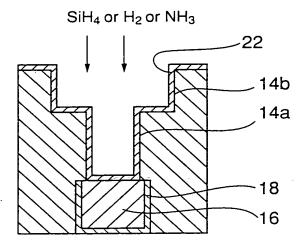


FIG. 6

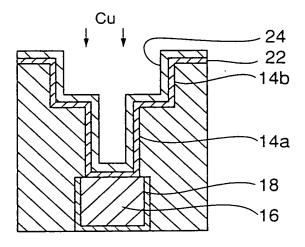


FIG. 7

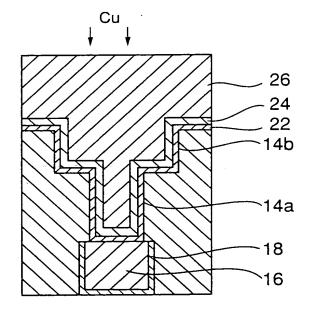


FIG. 8

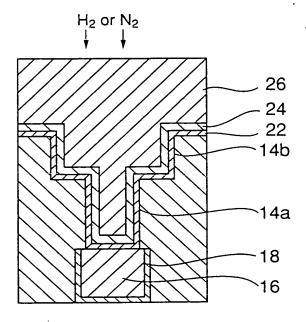


FIG. 9

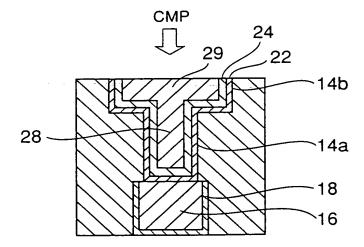


FIG.10

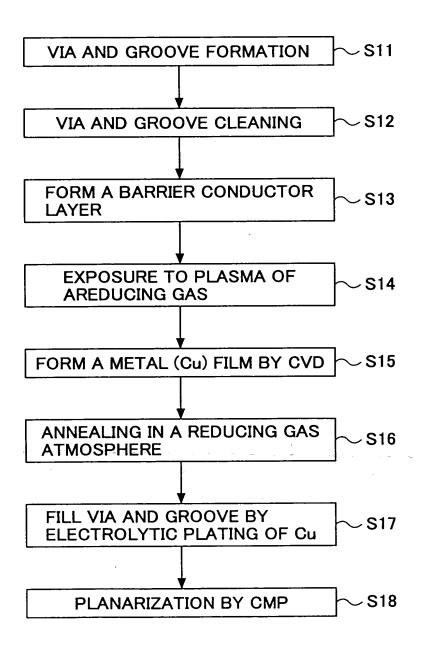


FIG. 11

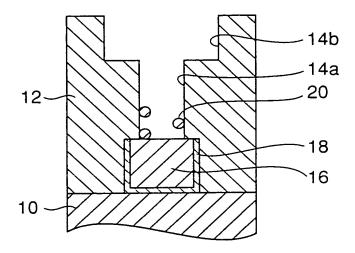


FIG. 12

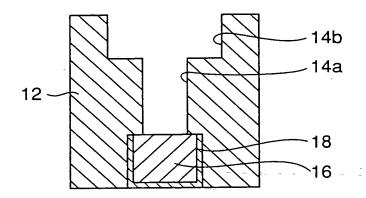


FIG. 13

30

14b

14a

18

16

FIG. 14

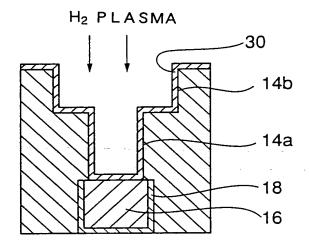


FIG. 15

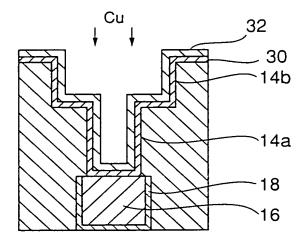


FIG. 16

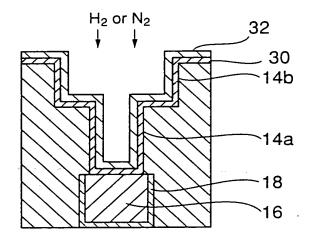


FIG. 17

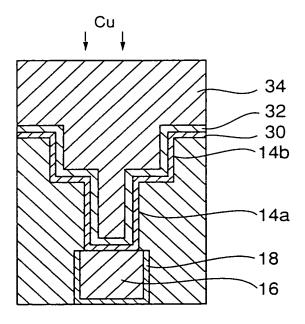


FIG. 18

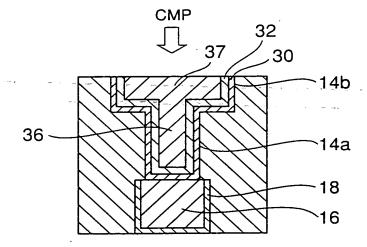


FIG 19

	BARRIER CONDUCTOR	METAL FILM	1st ANNEAL GAS	1st ANNEAL 2nd ANNEAL PLASMA GAS GAS	1	TAPE TEST	STRENGTH TEST (MPa)
EXP1	TaN(PVD)	Cu(CVD)	NH3	H2	_	0	68
EXP2	TaN(PVD)	Cu(CVD)	SiH4	H ₂	-	0	74
EXP3	TaN(PVD)	(GVD) _u O	H2	H ₂		0	69
EXP4	WN(CVD)	Cu(CVD)	SiH4	H ₂	_	0	64
EXP5	WN(CVD)	Cu(CVD)	_	ı	H ₂	0	75
COMP1	TaN(PVD)	Cu(CVD)	_	-	-	×	31
COMP2	TaN(PVD)	Cu(CVD)	-	H ₂	-	×	44
COMP3	TaN(PVD)	(GVD)	εHN	l	-	×	•
COMP4	TaN(PVD)	Cu(CVD)	SiH4	-	-	×	1
COMP5	TaN(PVD)	(CVD)	7H	-	_	×	
REF	TaN(PVD)	Cu(PVD) +Cu(CVD)	-	H2	l	0	69

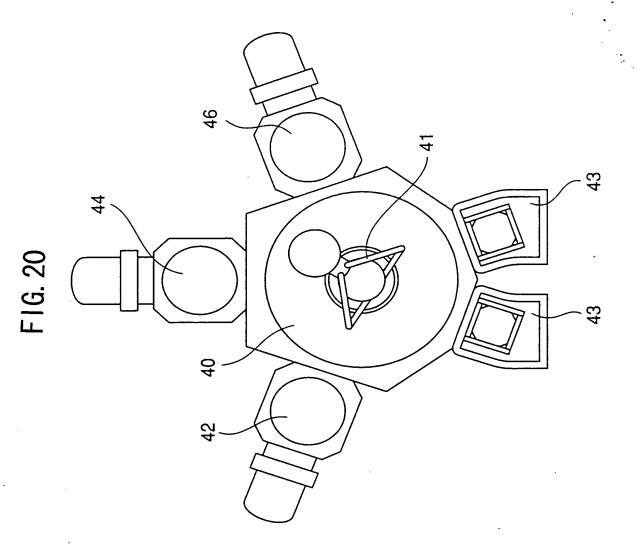


FIG.21

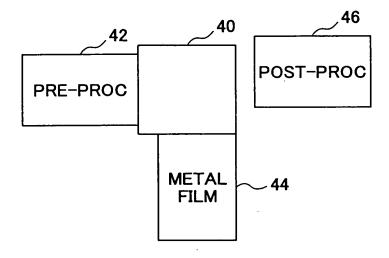


FIG.22

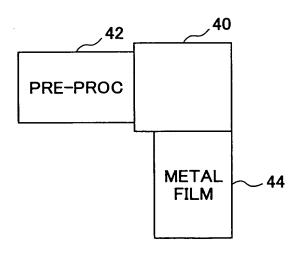


FIG.23

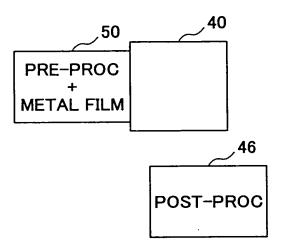


FIG.24

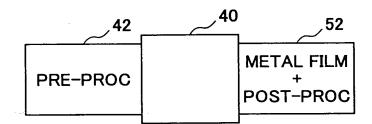


FIG.25

